

The microscopic nature of gettering defects at $R_p/2$ in high-energy self-implanted silicon



DRIP IX

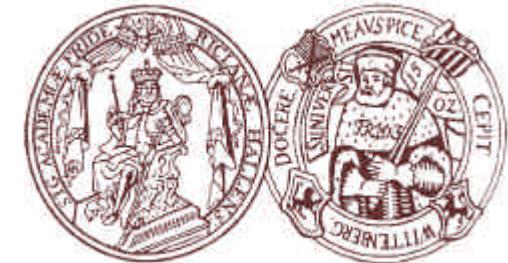
R. Krause-Rehberg¹, F. Börner¹, F. Redmann¹,
J. Gebauer¹, R. Kögler², W. Skorupa²,
G. Kögel³, W. Egger³, P. Sperr³, W. Triftshäuser³

¹Martin-Luther-Universität Halle-Wittenberg, Germany

²Forschungszentrum Rossendorf, Dresden, Germany

³Universität der Bundeswehr München, Germany

Martin-Luther-Universität



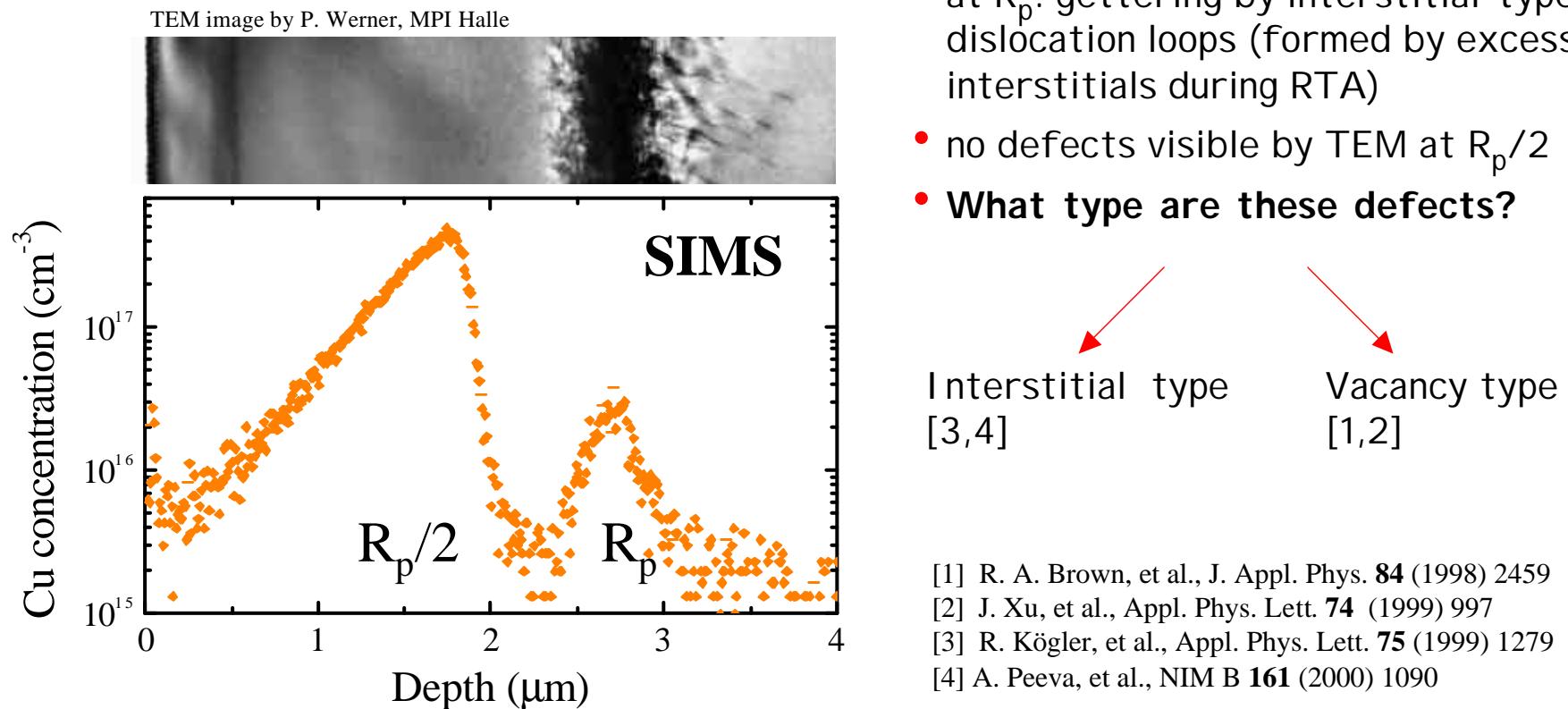
Halle-Wittenberg

- Introduction: The $R_p/2$ effect in Si
- Study using depth-resolution-enhanced Positron Beams
- Conclusions



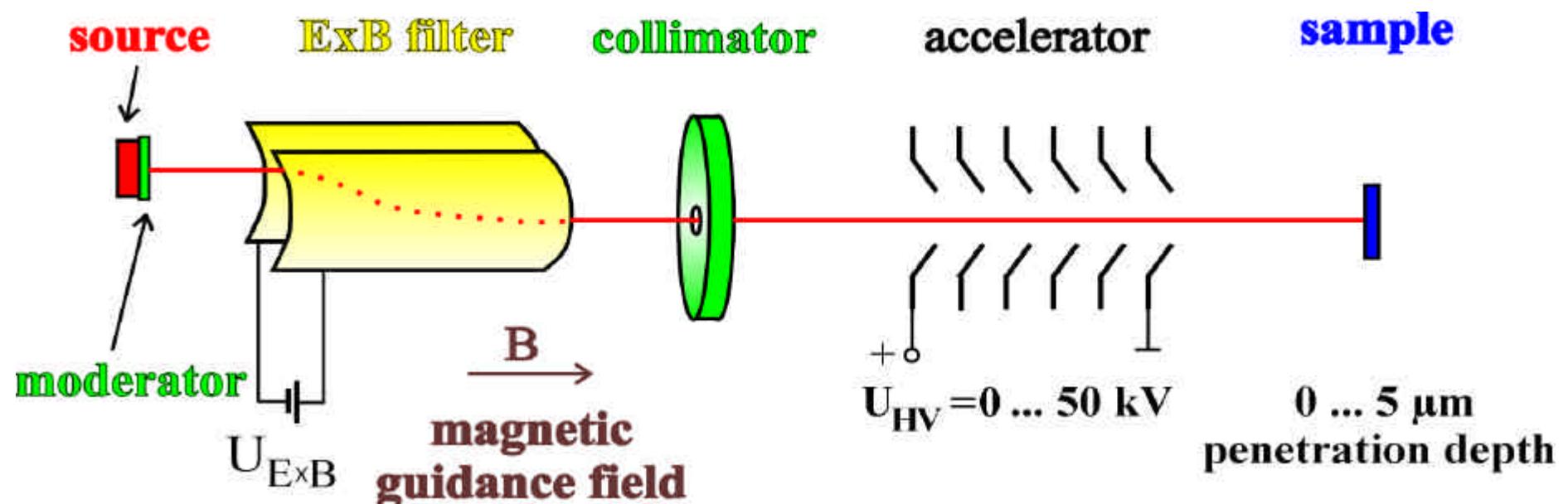
Defects in high-energy self-implanted Si ¾ The $R_p/2$ effect

- after high-energy (3.5 MeV) self-implantation of Si ($5 \cdot 10^{15} \text{ cm}^{-2}$) and RTA annealing (900°C , 30s): two new gettering zones appear at R_p and $R_p/2$ (R_p = projected range of Si^+)
- visible by SIMS profiling after intentional Cu contamination



Conventional positron beam technique

- positron annihilation successful in characterization of open-volume defects
- positron beam of mono-energetic positrons
- positrons are trapped at open-volume defects and change annihilation characteristics
- positron implantation depth varied by accelerating voltage (VEPAS)



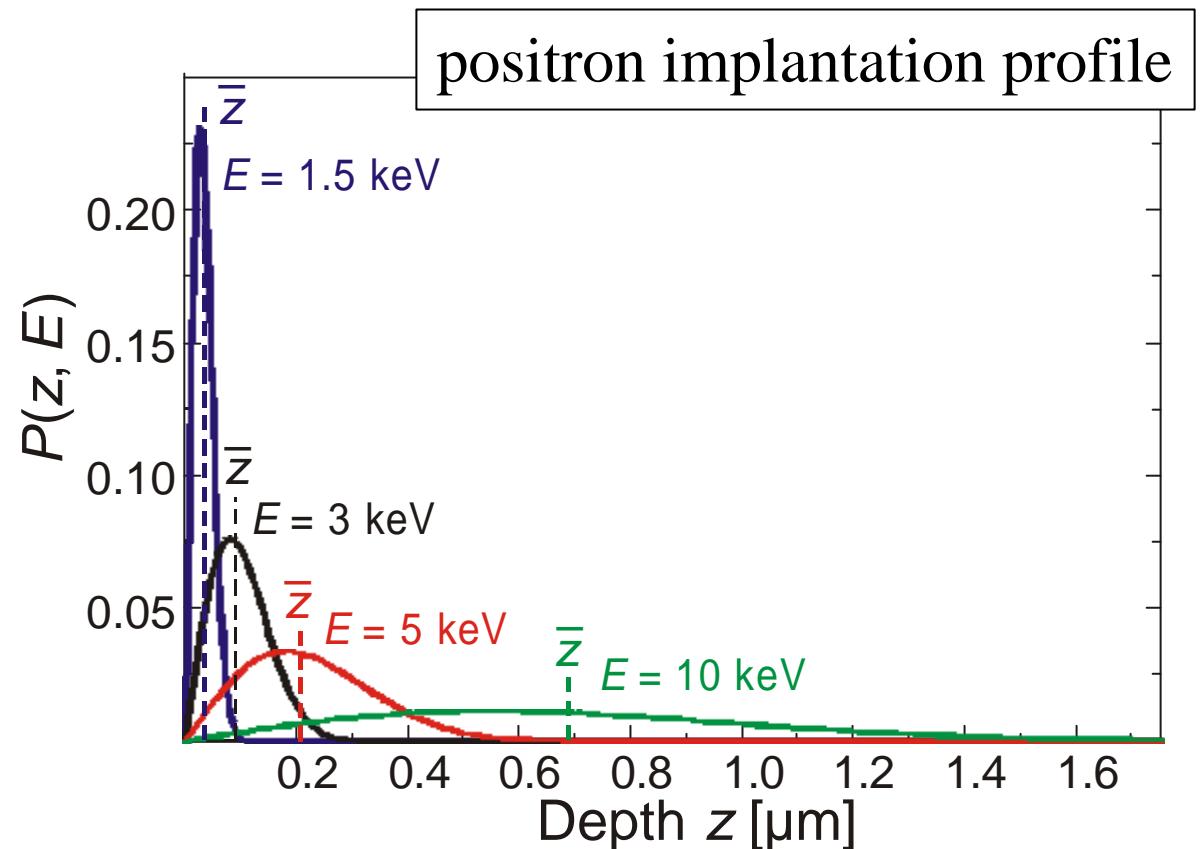
magnetically guided positron beam system at Univ. Halle

Positron beam measurement with enhanced depth resolution

- mono-energetic positrons exhibit broad implantation profile
- the defect layers are expected in a depth of $1.7 \mu\text{m}$ and $2.8 \mu\text{m}$ corresponding to $E_+ = 18$ and 25 keV
- implantation profile too broad to discriminate between the two zones

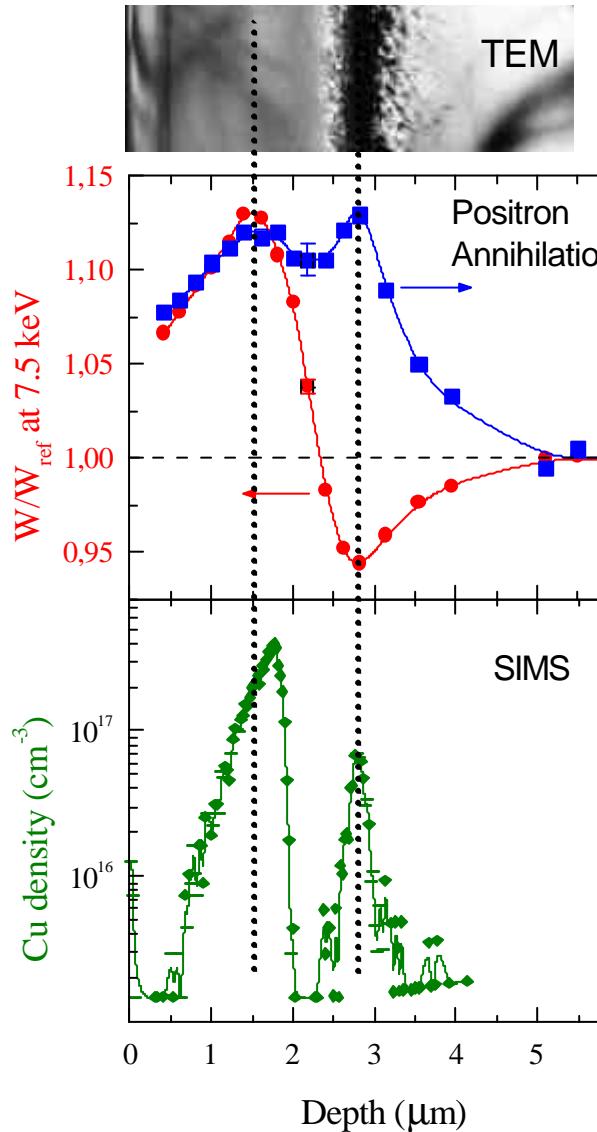
P

- step-by-step removal of sample surface by sputtering
- measurement at low e^+ energy with high depth resolution

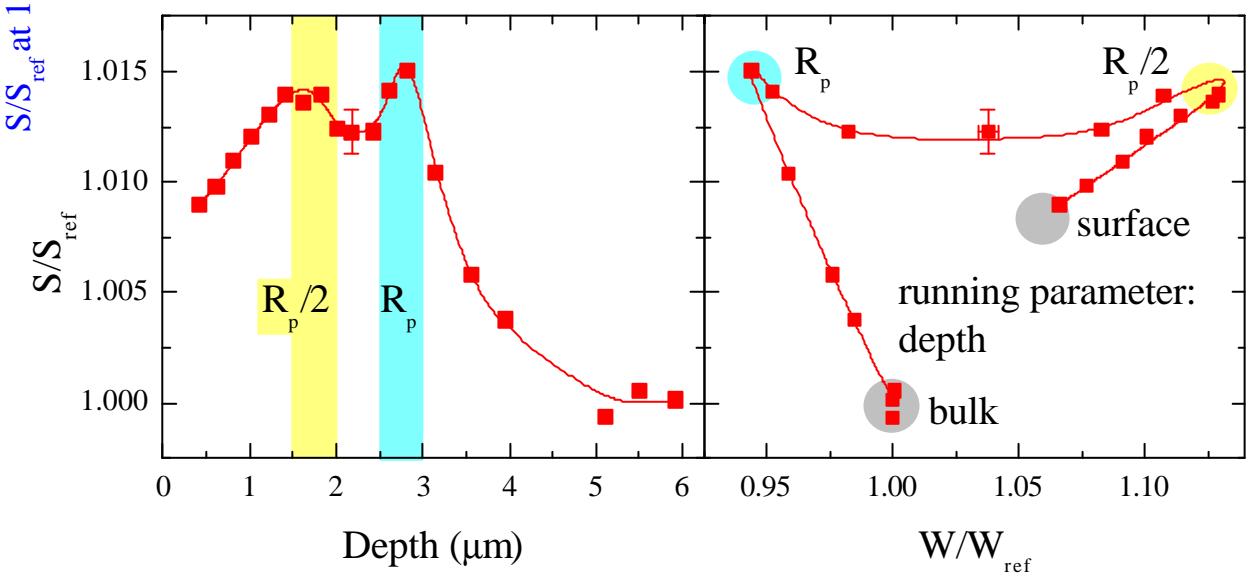


Getter centers after high-energy self-implantation in Si

surface $R_p/2$ R_p

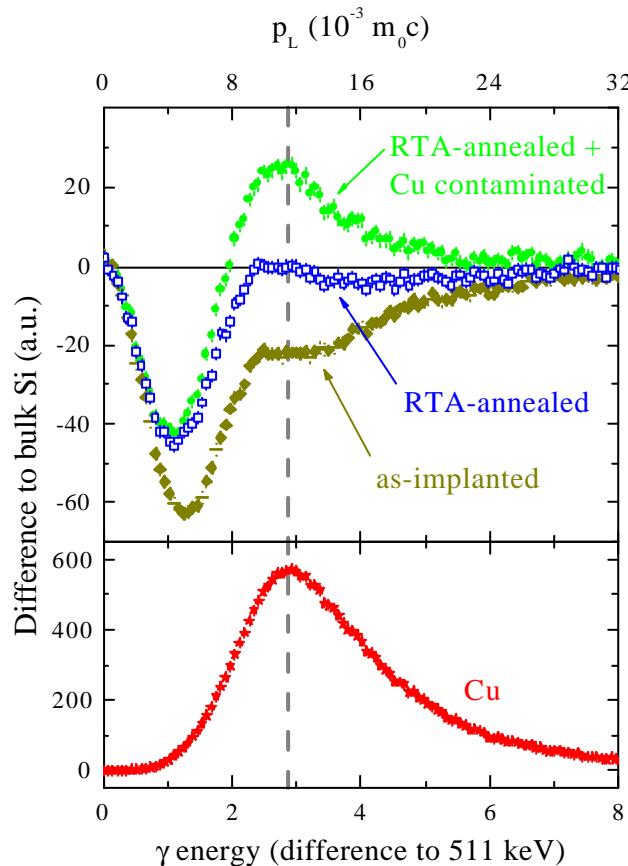


- VEPAS with improved depth resolution show clearly open-volume defects at $R_p/2$ and R_p
- they must be different (see S-W-plot)
- “normal” behavior of W parameter at R_p but high value at $R_p/2$: Cu decorates the vacancy-type defect

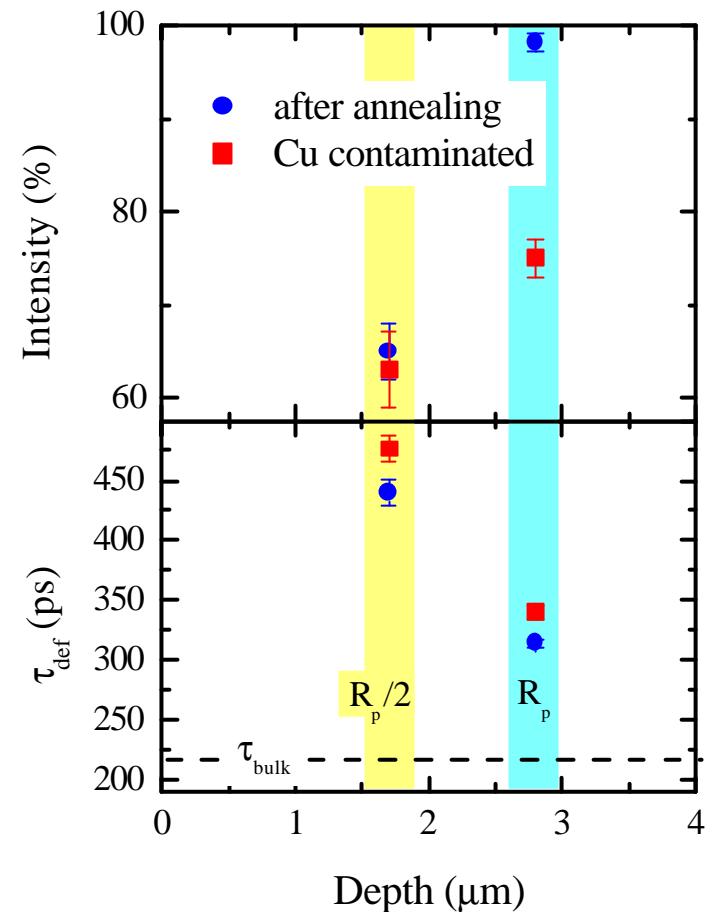


Doppler-coincidence and lifetime spectroscopy

- Doppler-coincidence spectroscopy shows the existence of Cu at the $R_p/2$ defect
- positron lifetime spectroscopy needed for determination of open volume size



- samples were chemically etched and positron lifetime was measured at Munich Slow-Positron Lifetime Beam System
- at $R_p/2$: $\tau_d = 450$ ps (vacancy cluster, $n > 10$)
- at R_p : $\tau_d = 320$ ps (open volume = divacancy)

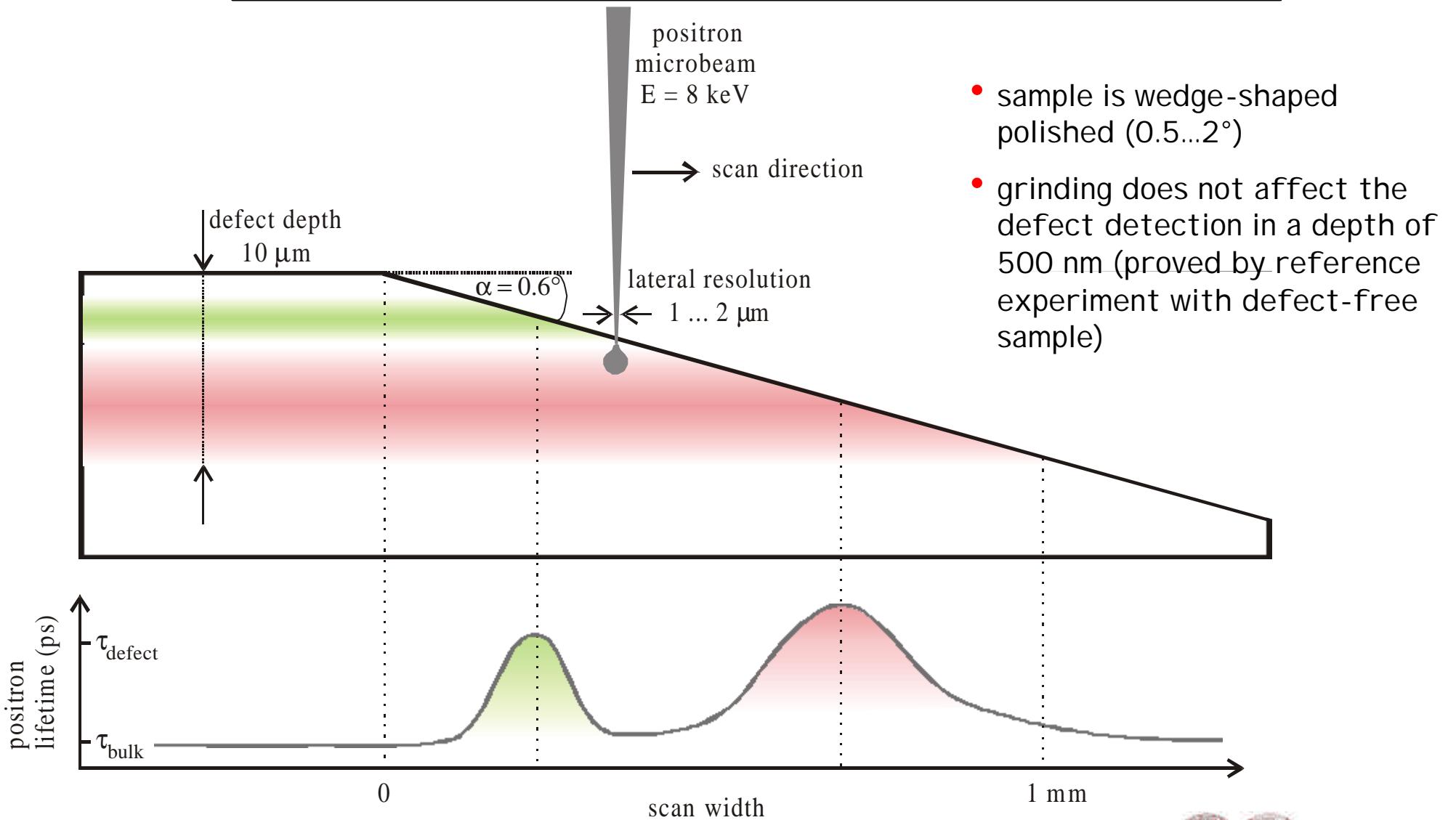


Conclusions

- $R_p/2$: small vacancy clusters are getter centers
- R_p : positrons are trapped by defects at dislocation loops

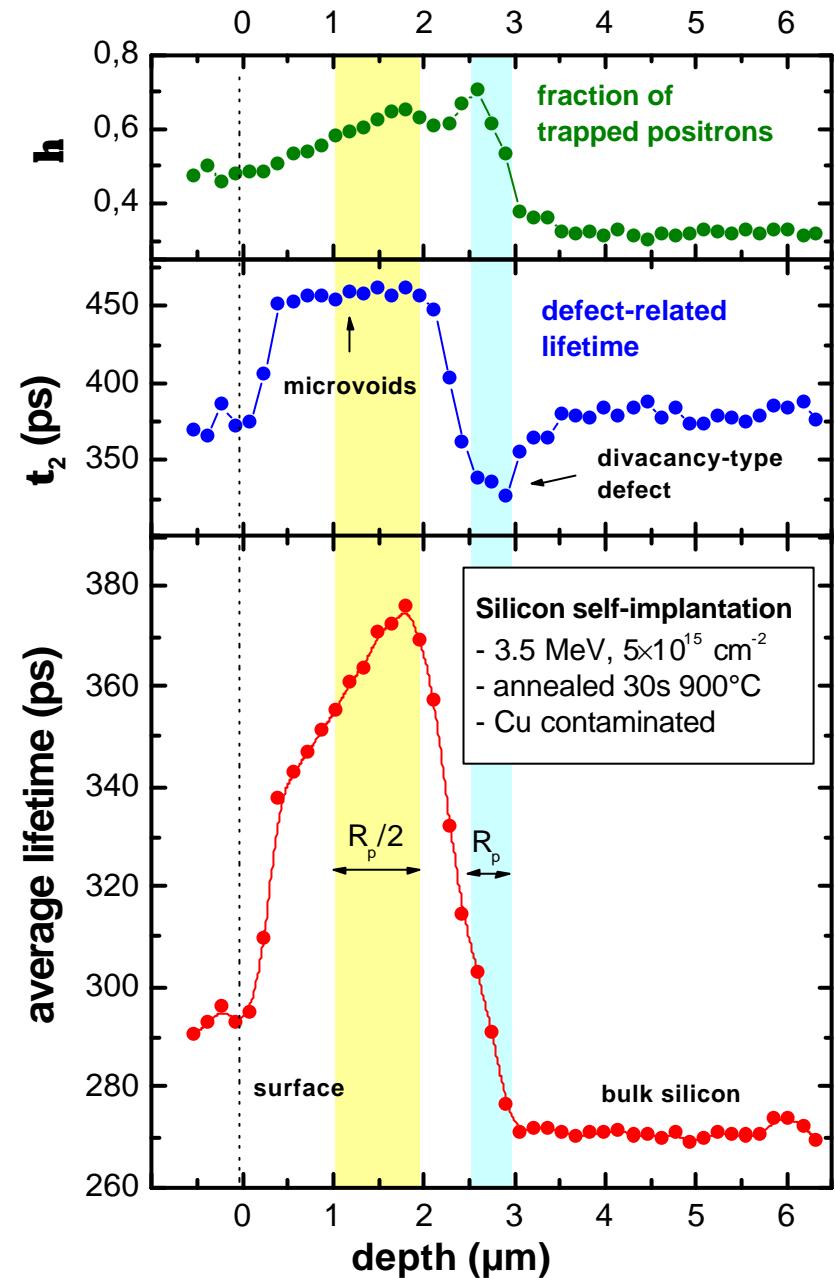


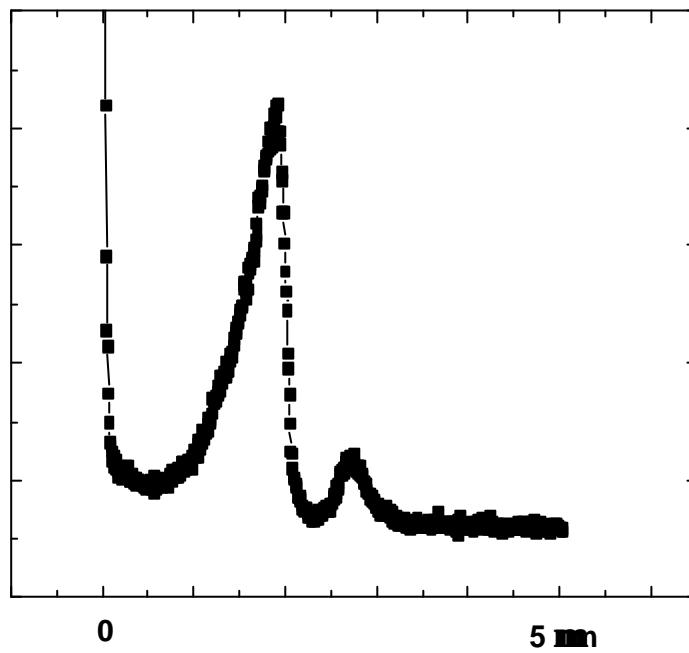
Enhanced depth resolution by using the Munich Scanning Positron Microscope



First defect depth profile using Positron Microscopy

- 45 lifetime spectra: scan along wedge
- separation of 11 µm between two measurements corresponds to depth difference of 155 nm ($\alpha = 0.81^\circ$)
- beam energy of 8 keV \mathbf{p} mean penetration depth is about 400 nm; represents optimum depth resolution
- no improvement possible due to positron diffusion: $L_+(Si @ 300K) \approx 230$ nm
- both regions well visible:
 - vacancy clusters with increasing density down to 2 µm ($R_p/2$ region)
 - in R_p region: lifetime $\tau_2 = 330$ ps; corresponds to open volume of a divacancy; must be stabilized or being part of interstitial-type dislocation loops





SIMS profile of Cu

Conclusions

- Vacancy agglomerates are the getter centers at $R_p/2$
- Depth profiling using positron microscope very promising

This presentation can be found as pdf-files on our Website:
<http://www.ep3.uni-halle.de/positrons>

